Atty. Docket No. OF03P106/US

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

:

Tae Woo KIM

: GROUP ART UNIT:

SERIAL NO: NEW APPLICATION

FILED: JULY 25, 2003

: EXAMINER:

FOR: METHOD FOR FABRICATING

MOS TRANSISTORS

I hereby certify that this document is being deposited with the United States Postal Service as first class mail in an envelope addressed to Commissioner for Patents, Washington, D.C. 20231, on <u>July 25, 2003</u>.

By: _

Andrew D. Fortney

REQUEST FOR PRIORITY UNDER 35 U.S.C. 119(a)-(b) AND 37 C.F.R. 1.55

COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

Applicant respectfully requests the benefit of the filing date of the following prior foreign application(s) under the Paris Convention for the Protection of Intellectual Property:

Serial No.

Filing Date

Country of Filing

10-2002-0043794

July 25, 2002

Republic of Korea

A certified copy of the priority application will be filed before any U.S. patent issues from the above-captioned application.

Respectfully submitted,

Andrew D. Fortney, Ph.D.

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